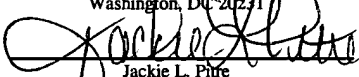




Application No.: 09/744,877  
Filed: January 29, 2001  
Inventor(s):  
Halimaoui et al.

Examiner: Novacek, Christy L.  
Group/Art Unit: 2822  
Atty. Dkt. No: 5310-03000

**Title:   PROCESS FOR FORMING  
AN OXIDE LAYER OF  
NON-UNIFORM  
THICKNESS ON THE  
SURFACE OF A SILICON  
SUBSTRATE**

CERTIFICATE OF MAILING  
 UNDER 37 C.F.R. §1.8  
 DATE OF DEPOSIT: 11-8-02  
 I hereby certify that this correspondence is being deposited with  
 the United States Postal Service with sufficient postage as first  
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 Commissioner for Patents  
 Washington, DC 20231  
  
 Jackie L. Pire

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
Washington, D.C. 20231

### Amendment

**Sir:**

Please amend the above-captioned application as follows:

***In the Claims:***

**Please cancel claims 1, 3-7, 9, 11, 12, and 14-17 without prejudice.**

11/25/2002	ACANTY	00000002	501505	09744977
01 FC:1202			324.00	CH
02 FC:1201			420.00	CH